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CML
or the STM controller 60 can either separately or together perform functions of the means for providing a carrier signal 40 and the means for reading and converting the output 42 (shown in Fig. 1).--

Page 15, line 26, delete the description of Fig. 2A, and insert the following: --Fig. 2A shows a probe mounted to a force sensor which interacts with a sample mounted upon a scanning head;--.

Page 29, line 18, delete "piezo electric", and insert in its place --piezoelectric--.

Page 30, line 3, delete "piezo electric", and insert in its place --piezoelectric--.

Page 31, line 9, delete "microindentation", and insert in its place --micro-indentation--.

Page 32, line 5, delete "piezo ceramic" and insert in its place --piezoceramic--.

In the Claims

Rewrite claim 41 as follows:

Sub
KI
41. (Amended) A scanned probe microscope apparatus having a probe and a scanning head operably arranged for measuring surface properties of a sample, the apparatus comprising:

a high precision capacitance sensor having a pick-up plate movably mounted relative to a drive plate;

means for transmitting force between an object remote from the pick-up plate and the pick-up plate; and

means responsive to the position of the pick-up plate relative to the drive plate for providing an output signal proportional to the relative position.

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